



제 29회 한국반도체학술대회

The 29th Korean Conference on Semiconductors

2022년 1월 24일(월)~ 26일(수) | 강원도 하이원 그랜드호텔(컨벤션타워)

2022년 1월 26일(수), 10:45-12:30

Room C (사파이어 I, 5층)

Q. Metrology, Inspection, Analysis, and Yield Enhancement 분과

[WC2-Q] Metrology, Inspection, and Yield Enhancement II

좌장: 강상우 소장(KRISS), 정용우 TL(SK 하이닉스)

<p>WC2-Q-1 10:45-11:15</p>	<p>Inline Convergence AFM Solutions 2022 for Semiconductor Industry Byoung-Woon Ahn, Ah-Jin Jo, and Sang-Joon Cho <i>Park Systems Co., Ltd.</i></p>
<p>WC2-Q-2 11:15-11:30</p>	<p>메모리소자의 나노미터 Trench 구조 계측을 통한 소자특성 분석 Haeri Kim, Dayeon Choi, Kyujin Choi, and Kyu Chan Shim <i>Research and Development Division, SK Hynix</i></p>
<p>WC2-Q-3 11:30-11:45</p>	<p>나노인덴테이션을 이용한 DRAM Low-k 박막 기계적 물성 분석 김재현 <i>SK Hynix</i></p>
<p>WC2-Q-4 11:45-12:00</p>	<p>기계 학습을 활용한 HAR 구조의 Profile 계측 배군호 <i>Advanced MI, SK Hynix</i></p>
<p>WC2-Q-5 12:00-12:15</p>	<p>TiN Film Growth Phase Monitoring Using Spectroscopic Ellipsometry Yong Woo Jung, Rae Seo Lee, Jin Ho Kim, Yu Seong Gim, Dong Gi Kim, Moon Gil Jung, and Dae Jong Kim <i>Ichon DRAM Metrology & Inspection Team, SK Hynix</i></p>
<p>WC2-Q-6 12:15-12:30</p>	<p>Physically Unclonable Function based on 2D MoS₂/WS₂-FET by Measurement and Characterization of Electrical Properties Jaeseo Park^{1,2}, Minji Park¹, Jung Woo Leem³, Zahyun Ku⁴, Jun Oh Kim¹, Won Chegal¹, Sang-Woo Kang^{1,2}, and Young L. Kim³ ¹Advanced Instrumentation Institute, KRISS, ²Science of Measurement, UST, ³Weldon School of Biomedical Engineering, Purdue University, ⁴Materials and Manufacturing Directorate, Air Force Research Laboratory</p>